

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) Substrate treatment equipment ~~having, comprising:~~
a substrate treatment chamber,
a substrate holder that can be inserted into the substrate treatment chamber and holds substrates in a multistage manner in a substantially vertical direction,
~~a substrate transfer unit for transferring the substrates into the substrate holder,~~
and
a sensing device for sensing a holding condition of the substrates held in the substrate holder; ~~characterized by including, holder,~~
a substrate transfer unit that transfers from the substrate holder substrates other than a substrate which was determined to be in an abnormal substrate holding condition according to a result of the sensing the holding condition of the substrates using the sensing device,
~~a control device that, in transfer of the substrates, senses the holding condition of the substrates using the sensing device, and controls the substrate transfer unit such that substrates other than a substrate which was determined to be in an abnormal substrate holding condition are transferred by~~ for controlling the substrate transfer unit.
2. (Currently Amended) The substrate treatment equipment according to claim 1, ~~characterized in that wherein the control device controls the substrate transfer unit such that~~ transfers the substrates other than the substrate determined to be abnormal and at least one of substrates held on and under the substrate determined to be abnormal ~~are transferred by the substrate transfer unit from the substrate holder.~~
- 3 - 4. (Canceled)

5. (New) The substrate treatment equipment according to claim 1, wherein the substrate transfer unit carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition.

6. (New) The substrate treatment equipment according to claim 2, wherein the substrate transfer unit carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition and at least one of substrates held on and under the substrate determined to be abnormal.

7. (New) The substrate treatment equipment according to claim 1, wherein the substrate transfer unit that senses the holding condition of the substrates using the sensing device, and when all of a predetermined number of substrates to be carried are determined to be in a normal substrate holding condition, carries together all the predetermined number of substrates, and when at least one of a substrate in the predetermined number of substrates is determined to be in the abnormal substrate holding condition, carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition in the predetermined number of substrates.

8. (New) The substrate treatment equipment according to claim 2, wherein the substrate transfer unit that senses the holding condition of the substrates using the sensing device, and when all of a predetermined number of substrates to be carried are determined to be in a normal substrate holding condition, carries together all the predetermined number of substrates, and when at least one of a substrate in the predetermined number of substrates is determined to be in the abnormal substrate holding condition, carries one at a time the substrates other than the substrate that was determined to be in the abnormal substrate holding condition and at least one of substrates held on and under the substrate determined to be abnormal in the predetermined number of substrates.